CAS Sesimbra, Portugal | March 14<sup>th</sup>, 2019

#### PLASMA SOURCES I

Research Group for Plasma Wakefield Accelerators **FLASH**FORWARD Deutsches Elektronen-Synchrotron DESY, Particle Physics Division, Hamburg, Germany

Accelerator Research and Development, Matter and Technologies Helmholtz Association of German Research Centres, Berlin, Germany

simulation by Alberto Martinez de la Ossa

X

#### **Jens Osterhoff**





## Many thanks for support and material to...

Simon Hooker (Oxford University) Nelson Lopes (IST Lisbon)

Disclaimer: presentation is only an incomplete and subjective snapshot of the field!

#### Timon Mehrling (LBNL) Greg Boyle, Severin Diederichs, Carl Lindstrøm, Kris Põder (all DESY)





Active plasma lens



#### AWAKE alkali vapor oven



Capillary discharge waveguide





Multi-compartment plasma cell



#### Gas jet

### **Lecture Series on Plasma Sources and Diagnostics**

#### > Plasma Sources I

- Thursday, March 14, 9:00 10:00
- Conceptual aspects
- > Plasma Sources II
  - Friday, March 15, 9:00 10:00
  - Technical aspects
- > Plasma Diagnostics
  - Tuesday, March 19, 10:00 11:00
  - **Diagnostics:** how to measure plasmas



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# technical compatibility?



- > Design aspects for a plasma source
- > Plasma generation mechanisms
- > Tailoring plasma properties to control wakefield and plasma processes



# technical compatibility?

#### **Design aspects**

> Adjustable plasma density n <sub>e</sub>	
> Tailored density profile n <sub>e</sub> (x,t)	
Defined (and adjustable) length L	
> Controlled species composition	

- > Controlled plasma temperature profile T<sub>e</sub>(x,t)
- > Spatial uniformity
- > Temporal stability





- > Durability (# of events)
- Support traversing of driver and witness
- > Accessible to diagnostics
- Materials and gas flow compatible with vacuum requirements

#### > Cost

### Plasma generation: ionization

### How to create a plasma

Plasma can be formed by different mechanisms

- Collisional ionization
  - discharges, laser-heated electrons, particle beams





e

#### Collisional

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  - discharges, laser-heated electrons, particle beams
- Single-photon ionization
  - high-energy photons:  $h v > I_p$





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  - discharges, laser-heated electrons, particle beams
- Single-photon ionization
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Keldysh parameter: 
$$\gamma_{\rm K} = \sqrt{\frac{I_{\rm P}}{2U_{\rm P}}}$$

- >  $\gamma_{\rm K}$  > 1  $\rightarrow$  Multi-photon ionization
- >  $\gamma_{\rm K} \ll 1 \rightarrow$  Field ionization (tunneling or barrier suppression)





## Multi-photon ionization (MPI)

> MPI typically relevant only for moderate laser intensities (or in temporal and spatial wings)

- Example:  $\gamma_{\rm K}$  > 1 for I < 1.1×10<sup>14</sup> W cm<sup>-2</sup> and  $\lambda$  = 800 nm
- > Ionization rate  $\Gamma_{i \rightarrow f} = \sigma_{i \rightarrow f}^{(N)} I^N$
- > Cross-section from Fermi's Golden Rule





## **Tunneling ionization**



- > External E-field comparable to binding field
- > External field distorts atomic potential
- > Valence electron can tunnel through barrier
- > Accurate solution can be found by solving the Schrödinger equation  $\rightarrow$  complex



> Described by simplified models, popular: ADK (Ammosov, Delone, and Krainov)

M. V. Ammosov *et al. Sov. Phys. JETP* **64** 1191 (1986) P. B. Corkum *Phys. Rev. Lett.* **71** 1994 (1993)

3/2/



Radius r (arb. units)

#### > ADK ionization rate

$$W[\text{fs}^{-1}] = 1.52 \times \frac{4^{n*}}{n*\Gamma(2n*)} \left(20.5\frac{E_I}{E}\right) \exp\left(-6.83\frac{E_I^{3/2}}{E}\right)$$
$$E_I = \text{Ionization potential (eV)}$$
$$E = \text{Electric field (GV / m)}$$
$$n* = 3.68Z/\sqrt{E_I} \quad \text{Effective quantum number}$$

## **Tunneling ionization**

> ADK ionization model only valid below

$$E_{crit} = \frac{1}{16Z} \left(\frac{U_{ion}}{U_H}\right)^2 E_{\alpha}$$
$$E_{\alpha} = m_e c \alpha^4 / r_e e \approx 5.14 \,\text{GV/cm}$$



> (Special case) model extensions exist. Care needed!

M. V. Ammosov *et al. Sov. Phys. JETP* **64** 1191 (1986) P. B. Corkum Phys. Rev. Lett. 71 1994 (1993)

1



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#### **Barrier suppression ionization**



(a) Noble gas ions

(b) Miscellaneous ions

Ion	$I_{\rm P}~({\rm eV})$	$I_{\rm BSI}~({\rm Wcm^{-2}})$
$\mathrm{He}^+$	24.59	$1.4\cdot 10^{15}$
$\mathrm{He}^{2+}$	54.42	$8.8\cdot10^{15}$
$\mathrm{Ne}^+$	21.6	$8.6 \cdot 10^{14}$
$\mathrm{Ne}^{2+}$	40.96	$2.8 \cdot 10^{15}$
$\mathrm{Ne}^{7+}$	207.3	$1.5 \cdot 10^{17}$
$\operatorname{Ar}^{8+}$	143.5	$2.6 \cdot 10^{16}$
$\mathrm{Xe}^+$	12.13	$8.6 \cdot 10^{13}$
$\mathrm{Xe}^{8+}$	105.9	$7.8 \cdot 10^{15}$

Ion	$I_{\rm P}~({\rm eV})$	$I_{\rm BSI}~({\rm Wcm^{-2}})$
$\mathrm{H}^+$	13.61	$1.4 \cdot 10^{14}$
$\mathrm{C}^+$	11.2	$6.4 \cdot 10^{13}$
$\mathrm{C}^{4+}$	64.5	$4.3 \cdot 10^{15}$
N $^{5+}$	97.9	$1.5 \cdot 10^{16}$
$O^{6+}$	138.1	$4.0 \cdot 10^{16}$



> At high fields the barrier is completely suppressed (Barrier Suppression Ionization)

$$I_{\rm BSI} \ge \frac{I_{\rm P}^4 \pi^2 c \epsilon_0^3}{2Z^2 e^6} \gtrsim 4.00 \cdot 10^9 \frac{I_{\rm P}^4}{Z^2}$$
 in W cm<sup>-2</sup> with  $[I_{\rm P}] = \text{eV}$ 

## Field ionization by particle beams

 $E_{r,\text{peak}}(r \approx 1.6\sigma_r)$ 



Courtesy Patric Muggli Max Planck Institute for Physics, Munich Coulomb fields of particle beams can trigger ionization
 Field maximum is off-axis for symmetric beams



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# Tailoring plasma properties to control wakefield processes

### What do we want to control?

#### > Plasma density $n_{e}(x,t), n_{i}(x,t)$

- injection (n<sub>e</sub> density down-ramps)
- dephasing (n<sub>e</sub> density up-ramps)
- laser guiding (transverse n<sub>e</sub> profiles)
- emittance preservation in beam release (tailored plasma to vacuum transition)
- emittance preservation in beam capturing/matching (tailored vacuum to plasma transition)
- hosing seed mitigation (tailored vacuum to plasma transition)
- head-erosion mitigation (preionized beam-driven)
- decoupled acceleration and focussing fields (hollow-core channels)
- positron acceleration (hollow-core channels)
- chirp mitigation (alternating plasma densities)



#### > Control: set parameters with high precision Stability: small event fluctuations

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- usually of lesser concern:  $T_{e/i} \approx I_p \ll U_p$
- important for non-wakefield applications, e.g. active plasma lenses



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#### > Plasma constituents (also from gas mixtures)

- unionized electronic levels  $\rightarrow$  ionization injection, ionization defocussing
- ion mass  $\rightarrow$  ion motion effects, thermal conductivity
- tracer atoms  $\rightarrow$  diagnostics



#### > Control: set parameters with high precision Stability: small event fluctuations

## Plasma density control

- > Plasma density n<sub>e</sub> (x,t) governs acceleration process
- > Usually: flat acceleration section





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## Plasma density control - down-ramp injection

> Plasma density n<sub>e</sub> (x,t) governs acceleration process



- Phase velocity of plasma wake reduced on density down-slope
- Velocity of plasma electrons may exceed v<sub>0</sub>, leads to trapping
- > Trapping possible in multiple buckets

![](_page_29_Picture_6.jpeg)

## Plasma density control - phase locking

> Plasma density n<sub>e</sub> (x,t) governs acceleration process

DESY.

![](_page_30_Figure_2.jpeg)

![](_page_30_Figure_3.jpeg)

- > Phase velocity of plasma wake increased on density up-slope
- Plasma wave phase velocity v<sub>Φ</sub> may be locked to velocity of injected beam
- > Electrons can be locked in acceleration phase

Rittershofer et al., Phys. Plasmas 17, 063104 (2010)

## **Plasma density control - beam release**

> Plasma density n<sub>e</sub> (x,t) governs acceleration process

![](_page_31_Picture_2.jpeg)

> Beams at plasma exit

- ~% level energy spread
- *≤* mm beta function, ~mrad divergence

> Leads to transverse emittance growth in free drift

$$\varepsilon_n^2 \cong \langle \gamma \rangle^2 \cdot (\sigma_E^2 \sigma_{x'}^4 s^2 + \varepsilon^2)$$

→ K. Floettmann, Phys. Rev. STAB 6, 034202 (2003)

$$\epsilon = \sqrt{\langle}$$

![](_page_31_Picture_10.jpeg)

## **Plasma density control - beam release**

> Plasma density n<sub>e</sub> (x,t) governs acceleration process

![](_page_32_Figure_2.jpeg)

> Beams at plasma exit

- ~% level energy spread
- ≤ mm beta function, ~mrad divergence
- > Leads to transverse emittance growth in free drift
- > Plasma-to-vacuum transition length  $\gg \beta$ for adiabatic mitigation of emittance growth
- Strong focussing elements for beam capturing required

![](_page_32_Picture_9.jpeg)

## **Plasma density control - beam capturing/matching**

> Plasma density n<sub>e</sub> (x,t) governs acceleration process

![](_page_33_Figure_2.jpeg)

> External beams need to be matched to wakefield to preserve normalized emittance

![](_page_33_Picture_5.jpeg)

## Plasma density control - beam capturing/matching

> Plasma density n<sub>e</sub> (x,t) governs acceleration process

![](_page_34_Figure_2.jpeg)

External beams need to be matched to wakefield to preserve normalized emittance

![](_page_34_Figure_4.jpeg)

## **Plasma density control - beam capturing/matching**

> Plasma density n<sub>e</sub> (x,t) governs acceleration process

![](_page_35_Figure_2.jpeg)

- External beams need to be matched to wakefield to preserve normalized emittance
- > Matching conditions

$$\alpha_{match} = 0 \qquad \beta_{match} \simeq \frac{c}{\omega_{\beta}}$$

- > Matched  $\beta$  (~ mm) can be challenging to achieve
- > If matching technically difficult, adiabatic up-ramp may help

![](_page_35_Picture_9.jpeg)

#### **Centroid equations**

Beam centroid equation

$$\frac{\partial^2 X_b}{\partial t^2} + \omega_\beta^2 \left( X_b - X_c \right) = 0$$

Channel centroid equation assuming linear plasma sheath response\*  $\frac{\partial^2 X_c}{\partial \xi^2} + \frac{k_p^2}{2} \left( X_c - X_b \right) = 0$ 

Channel centroid equation including relativistic sheath electrons and varying current and blowout radius along beam\*\*

$$\frac{\partial^2 X_c}{\partial \xi^2} + \frac{k_p^2 c_{\psi}(\xi) c_r(\xi)}{2} \left( X_c - X_b \right) = 0$$
$$c_r(\xi) = 4I_b(\xi) / I_A(k_p R(\xi))^2$$
$$c_{\psi}(\xi) = 1 / (1 + \psi(\xi))$$

#### **Dramatic implications for PWFA**

Beam centroid deviations are amplified exponentially in time and along the beam!

\*D. H. Whittum, et al. Phys. Rev. Lett. 67, 991 (1991). \*\*C. Huang, et al. Phys. Rev. Lett. 99, 255001 (2007).

![](_page_36_Figure_10.jpeg)

![](_page_36_Picture_11.jpeg)

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![](_page_37_Figure_12.jpeg)

![](_page_37_Picture_13.jpeg)

Excellent agreement between analytical estimates, numerical solution and PIC\*

![](_page_38_Figure_2.jpeg)

![](_page_38_Picture_3.jpeg)

\* T. J. Mehrling et al., PRL 118, 174801 (2017)

Excellent agreement between analytical estimates, numerical solution and PIC\*

![](_page_39_Figure_2.jpeg)

![](_page_39_Figure_3.jpeg)

![](_page_39_Picture_4.jpeg)

\* T. J. Mehrling et al., PRL 118, 174801 (2017)

> Linear scalings for LWFAs

- Accelerating field  $E_z \propto \omega_p \propto \sqrt{n_e}$
- Dephasing length
- Energy gain

$$L_d \approx \frac{\lambda_p^3}{\lambda^2} \propto \frac{1}{n_e^{3/2}}$$
$$\Delta W = E_z L_d \propto \frac{1}{n_e}$$

![](_page_40_Picture_6.jpeg)

Simple scaling (in linear regime) shows, factor 10 increase in energy requires:

- Factor 10 decrease in electron density:
   10<sup>19</sup> cm<sup>-3</sup> → 10<sup>18</sup> cm<sup>-3</sup> → 10<sup>17</sup> cm<sup>-3</sup>
- Factor 30 increase in length:
  - 1 2 mm → 30 60 mm → 900 1800 mm

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![](_page_41_Figure_6.jpeg)

![](_page_41_Picture_7.jpeg)

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- Factor 30 increase in length:
   1 2 mm → 30 60 mm → 900 1800 mm

The laser intensity must be maintained over the acceleration length

- limited by laser diffraction
- Rayleigh range typically only millimeters

Example :

 $w_0 = 10 \,\mu\mathrm{m}; \,\lambda = 1 \,\mu\mathrm{m}$ 

 $\Rightarrow Z_R = 0.3 \,\mathrm{mm}$ 

> Transverse index of refraction gradient may guide lasers

![](_page_42_Picture_2.jpeg)

![](_page_42_Picture_4.jpeg)

- > Transverse index of refraction gradient may guide lasers
- > Plasma channel: transverse variation of electron density gives correct refractive index profile
  - Transverse plasma density gradient gives transverse index of refraction gradient

$$\eta = \sqrt{1 - \left(\frac{\omega_p}{\omega}\right)^2}$$
 $pprox 1 - \frac{1}{2} \frac{n_e(r)e^2}{\gamma m_e \epsilon_0 \omega^2}$ 

- Changes laser phase velocity  $v_{\phi} = c/\eta$
- > Parabolic channel will match Gaussian beam of spot size W
- > Shape of channel is not very important: matched spot size mainly determined by channel depth
  - cf. Durfee et al., Opt. Lett. 19, 1937 (1994)

![](_page_43_Picture_9.jpeg)

![](_page_43_Figure_12.jpeg)

$$V_M = \left(\frac{r_{ch}^2}{\pi r_e \Delta n_e}\right)^{1/4} \qquad n_e(r) = n_e(0) + \Delta n_e \left(r/r_{ch}\right)^2$$

> Relativistic self-focusing: transverse variation of intensity gives correct refractive index profile

- Leads to self-focusing/guiding above a critical power

$$P_c = 17.4 \left(\frac{\omega}{\omega_p}\right)^2 \,\mathrm{GW} \qquad \qquad \mathbf{X}$$

Example

$$n_e = 10^{18} \,\mathrm{cm}^{-3}, \lambda = 800 \,\mathrm{nm}$$
  
 $P_c = 8 \,\mathrm{TW}$ 

![](_page_44_Picture_6.jpeg)

![](_page_44_Figure_8.jpeg)

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![](_page_45_Picture_6.jpeg)

S. Kneip et al., Phys. Rev. Lett. 103 035002 (2009)

![](_page_45_Figure_9.jpeg)

## **Plasma density control - hollow core channels**

![](_page_46_Figure_1.jpeg)

## Plasma density control - head erosion mitigation

- > Front of drive beam
   not in focussing channel
   → front is diverging
- > Beam erodes from the front "head erosion"
- > Etching speed scales with

$$\epsilon_N/\gamma N^{1.5}$$

![](_page_47_Figure_5.jpeg)

from An et al., Phys. Rev. STAB 16, 101301 (2013)

![](_page_47_Picture_7.jpeg)

## **Plasma density control - head erosion mitigation**

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$$\epsilon_N/\gamma N^{1.5}$$

> Laser preionization provides focussing plasma for front of beam

![](_page_48_Figure_6.jpeg)

![](_page_48_Picture_7.jpeg)

![](_page_48_Figure_8.jpeg)

![](_page_48_Figure_10.jpeg)

## **Plasma density control - chirp mitigation**

![](_page_49_Figure_4.jpeg)

![](_page_49_Picture_5.jpeg)

## **Plasma constituents control - ionization injection**

![](_page_50_Figure_1.jpeg)

Ionization of dopant gas near laser-pulse peak intensityDopant concentration

to tune injected charge and beam loading

*idea:* D.Umstadter *et al.*, Phys. Rev. Lett. **76**, 2073 (1996) *demonstration:* A.Pak *et al.*, Phys. Rev. Lett. **104**, 025003 (2010) C.McGuffey *et al.*, Phys. Rev. Lett. **104**, 025004 (2010)

#### **Plasma temperature control**

- > Initial plasma temperature  $T_e(x,t)$ ,  $T_i(x,t)$  usually small compared to Up  $\rightarrow$  effects usually neglected
- Influences wave-breaking threshold only at very high plasma temperatures

![](_page_51_Figure_3.jpeg)

![](_page_51_Picture_4.jpeg)

#### $\mu = 3k_{\rm B}T_{\rm e}(m_{\rm e}v_{\rm p}^2)^{-1}$

## **Plasma temperature control - APLs**

> Temperature control of crucial importance for active plasma lenses

![](_page_52_Figure_2.jpeg)

 $\rightarrow$  F = I x B, tunable and symmetric focussing force for e<sup>-</sup>-beam

J. van Tilborg et al., Phys. Rev. Lett. 115, 184802 (2015)

![](_page_52_Picture_5.jpeg)

![](_page_52_Picture_7.jpeg)

![](_page_53_Figure_2.jpeg)

- - results in transverse density and temperature gradient
  - ohmic resistance depends on temperature
  - local current density depends on local temperature
  - leads to B-field inhomogeneities  $\rightarrow$  nonlinear focussing fields  $\rightarrow$  emittance growth

![](_page_53_Picture_10.jpeg)

![](_page_53_Figure_11.jpeg)

Cap wall

at r=R

## **Plasma temperature control - APLs**

> Temperature control of crucial importance for active plasma lenses

![](_page_54_Figure_2.jpeg)

#### > Plasma heated by current, cooled on walls

- results in transverse density and temperature gradient
- ohmic resistance depends on temperature
- local current density depends on local temperature
- leads to B-field inhomogeneities  $\rightarrow$  nonlinear focussing fields  $\rightarrow$  emittance growth

![](_page_54_Picture_8.jpeg)

![](_page_54_Picture_10.jpeg)

![](_page_54_Figure_11.jpeg)

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![](_page_55_Figure_2.jpeg)

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![](_page_55_Picture_8.jpeg)

> APLs need to be used long before thermal equilibrium is reached, when current density is still uniform

![](_page_55_Picture_11.jpeg)

![](_page_55_Figure_12.jpeg)

![](_page_56_Figure_2.jpeg)

- Substitute Hydrogen/Helium with Argon to extend timescale of temperature equilibration ~ mion
- > Experiment at CLEAR, CERN: 216 MeV electrons, 50 µm rms size, 3 µm norm. emittance, 410 A current at 70 ns
- > Argon: emittance conservation measured Helium: emittance not conserved

![](_page_56_Picture_6.jpeg)

## Summary of Plasma Sources I

> Today

- **Design aspects for a plasma source**
- **Concepts:** plasma generation mechanisms
- **Concepts:** tailoring plasma properties to control wakefield processes

> Tomorrow: technical implementation and examples

![](_page_57_Picture_6.jpeg)

![](_page_57_Picture_7.jpeg)